SimuLED™

Engineering software package for LED design and optimization

www.str-soft.com

Prehistory of STR:

1984: Start of the MOCVD modeling activities at Ioffe Institute, St. Petersburg, Russia

1993-1996: Group for modeling of crystal growth and epitaxy at University of Erlangen-Nuernberg, Germany

History of software development

2000: Launch of development of the first specialized software 2003: First release of commercial software package 2004: First release of the software for device engineering

STR Today:

More than 40 scientists and software engineers

STRALLA

3 – Local distributors

Bulk crystal growth modeling (Si, Ge, SiGe, GaAs, InP, SiC, AIN, Al₂O₃, Optical Crystals) **Epitaxy and deposition modeling (Si, SiGe, SiC, AlGaAs, AlGaInP, AlGaInN, high-k oxides) Modeling of device operation (LEDs, Laser Diodes, FETs/HEMTs Shottky diodes)**

STR activity in software development

and consulting service

Software & consulting services :

- Modeling of crystal growth from the melts and solutions: CGSim
- Modeling of polysilicon deposition by Siemens process: PolySim
- Modeling of bulk crystal growth of SiC, AlN, GaN: ViR
- Modeling of epitaxy of compound semiconductors: CVDSim
- Modeling of optoelectronic and electronic devices: SimuLED

Customer base:

- More than 160 companies and universities worldwide
- Top LED, LD and solar cell manufacturers
- Top sapphire, GaAs, GaP, GaN, AlN and SiC wafer manufacturers
- Top MOCVD reactor manufacturers

Multidisciplinary

- **- materials science**
- **- physics of semiconductors**
- **- heat transfer theory**
- **- optics**

Essentially nonlinear

- **- nonuniform voltage drop and IQE distributions over the active region**
- **- self-heating in active region**
- **- current crowding results in nonuniform light intensity distribution over the active region**

Multidimensional and multiscale

- **- QW thickness is ~2-10nm**
- **- chip size is ~300µm**
- **- luminary size is ~10mm**

General purpose software SimuLED™

We reject the idea of "homogeneous approach for simulation of multiphysics and multiscale problem" applied for the whole LED at all space scales

In SimuLED, we replace the homogeneous model by a set of coupled submodels \Rightarrow

For each submodel:

- **Dominant physics**
- **Appropriate dimensionality**
- **Appropriate computational domain**

SimuLED submodels are realized as modules:

- Carrier transport through the active region: $1D + b$ ipolar carrier transport $\Rightarrow j_z(U_b, T)$, $\eta_{\text{int}}(U_{b},T)$, and λ
- Current spreading in LED die: 3D + unipolar carrier transport + active region replaced by nonlinear resistance \Rightarrow W(x,y)
- Light propagation in the LED die: $3D \Leftrightarrow EQE$, P_{out} , WPE

Basic tools of SimuLED™ software package

SiLENSe™: module for designing of LED/LD heterostructure

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Structure

Parameters computed with SiLENSe™

- **Band diagrams**
- **Carrier concentrations**
- **Electric field**
- **Rrad, Ri nonrad, IQE**
- **Carrier fluxes and leakages**
- **Energy levels in QWs**
- **Emission and gain spectra**

SiLENSe is supplied with the editable database of materials properties

SimuLED hybrid approach: SpeCLED/RATRO coupling

n-contact layer textured surface n-electrode n-contact layer n-pad η_{int} -0.6 -0.55 -0.5 -0.45 -0.4 -0.36 **active region SpeCLED computations p-contact layer highly** $W = \frac{j_z(x, y)}{i \hbar \omega \cdot \eta}$ $\frac{(x, y)}{y} \cdot \hbar \omega \cdot \eta_{\text{int}}(x, y)$ **reflective pelectrode** *q* Non-uniform distribution of light emission from the active region **jz, A/cm2** 661 533 406 -278 -150 .
م ب -23 **RATRO**

Parameters computed with SpeCLED™

- **3D distributions of the electric potential, current density, and temperature in the whole die**
- **2D distributions of the p-n junction bias, current density, IQE, and temperature in the active region plane**
- **I-V characteristic**
- **Series resistance**
- **EQE and WPE**

Planar chip design typical for LEDs fabricated on sapphire substrate

Conventional LED A = 0.0466 mm2 ; substrate-down mounting

Current crowding and in-plane temperature non-uniformity

Current crowding occurring at the electrode edge (I = 80 mA) produces a very nonuniform in-plane EL intensity distribution

RATRO™: 3D ray-tracing analysis of optical

characteristics of LED dice

Parameters computed with RATRO™

Light extraction efficiency

from an LED die

Far- and near-field emission

patterns

- **Light polarization distribution new**
- **Consideration of non-uniform**

electroluminescence intensity

distribution in the active region plane

 Various die configurations, including shaped substrate are supported

electrodes

Model of light transmission

Competitive Advantage

through semitransparent

multilayer metallic

… the user obtains angle-dependent reflection, transmission, and absorption coefficients of DBR surface

60

90

120

Optimization of electrode configuration to suppress

current crowding

Electroluminesence from blue LED chip

http://www.sle.sharp.co.uk/research/advanced_optoelectronics/blue_leds.php

Modeling software such as SpeCLED is used to optimize the LED chip design in order to improve operating voltage, light extraction efficiency and junction temperature. Other tools such as SiLENSe are also available to model band diagrams and to understand fundamental theoretical work, such as the piezoelectric effect in nitridebased devices.

LED chip design using SpeCLED

Enhancement of light extraction in ultraviolet light-emitting diodes using nanopixel contact design with AI reflector

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We report on a nanopixel contact design for nitride-based ultraviolet light-emitting diodes to enhance light extraction. The structure consists of arrays of Pd ohmic contact pixels and an overlying Al reflector layer. Based on this design a twofold increase in the light output, compared to large area Pd square contacts is demonstrated. Theoretical calculations and experiments reveal that a nanopixel spacing of 1 μ m or less is required to enable current overlap in the region between the nanopixels due to current spreading in the p-GaN layer and to ensure current injection into the entire active region. Light emitted in the region between the nanopixels will be reflected by the Al layer enhancing the light output. The dependence of the light extraction on the nanopixel size and spacing is investigated. © 2010 American Institute of Physics. [doi:10.1063/1.3334721]

Schematic cross-sectional view of nitride-based nanopixel UV LED with Pd contacts and Al reflector layer

Simulation of the current injection in the active region for nanopixel AlInGaN LEDs with nanopixel size 1x1 μm2 and nanopixel spacing (a) 4μ m, (b) 2μ m, and (c) 1μ m. The total current is constant. In the graph the injection current density as a function of the position along a line through the center of the nanopixels is shown for the different structures.

A nanopixel LED design with an Al reflector was developed resulting in enhanced light extraction in UV LEDs.

current crowding

Optimization of electrode configuration in large GalnN light-emitting diodes

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simulations allowed authors to design electrode configuration for a uniform current injection in a large GaInN LED chip and demonstrated an increase in output power in an optimized device.

Figure 5 Normalized EQE versus current density of actual devices.

3. Operation of modern light emitters

A. Use of ITO spreading layer for improvement of LED performance

Factors affecting the overall LED efficiency

Current crowding in LED dice with various ITO thickness at 20 mA

Current density distribution across the LED active region, A/cm2

increasing ITO layer thickness (electrical sheet conductivity) results in redistribution of the current density but does not avoid the current crowding; moreover, the higher the sheet conductivity, the stronger becomes current crowding near the n-electrode edge !!

IQE distribution in the LED die at 20 mA

0.53

Near-field emission intensity distribution at 20 mA

Total LEE is ~1.5-2.0 time higher than in the LED with metallic p-electrode

Characteristics of basic Thin-Film LED die

B. Operation of Interdigitated multi-pixel array (IMPA)

30 **Design of LED array was suggested by A. Chakraborty et al. (UCSB), Appl.Phys.Lett 88 (2006) 181120**

Comparison of LEDs with IMPA and conventional square chip designs

300×300 μm2 square LED

Interdigitated multi-pixel array (IMPA) containing a hundred of 30×30 μm2 pixels

top view bottom view

Overheating of square die does not allow power increase higher than 25 mW, whereas the dependence of power on current for IMPA die is close to linear up to current about 0.8 mA

Due to suppressed current crowding and reduced overheating, the IMPA LED is capable of high current operation without significant droop of the EQE at the currents from 1 to 3 A

C. Analysis of Thin-Film LED operation

Basic design of 815×875 μm2 blue LED die

Current crowding near/under n-electrode at 700 mA

Emission intensity and probability of light extraction in the active region

maximum of emission intensity is located under/next to n-electrode, despite the IQE droop with current; light emission under the n-pad does not contribute at all to the extracted light !! NB!

probability of light extraction falls down under and next to n-electrode

Characteristics of basic Thin-Film LED die

Two approaches for improvement of Thin-Film LED performance

Approach 1: insertion of a current blocking layer (thin insulating film) under the n-pad to avoid parasitic current flowing in this region

Approach 2: use of refined electrode structure with larger number of Г-shaped electrode branches but with smaller width of each of them

Current spreading in LED dice of improved design

 $\frac{1}{2}$ **Total current through the diode I = 700 mA**

Local probability of light extraction from improved LED dice

 $\frac{1}{2}$ **Total current through the diode I = 700 mA**

Assessment of performance improvement due to variation of LED die design

- **Consulting service & software support:** *simuled-support@str-soft.com*
- **Information on commercial software** *www.str-soft.com*

- **Demo version**
- **Physical summary**
- **Code description**
- **GUI manual**
- **SimuLED tutorials**

Detailed info is available upon request:

• Demo version

• Physical summary

• Code description

• GUI manual

• GUI manual

STR currently provides software and consulting services to over 40 companies and Academic Institutions in USA, Europe, and Asia.

- Anna University, India
- University of Maryland, Department of Electrical and Computer Engineering
- ECE Dep. and Nano Tech Center, Texas Tech Univ., USA
- Chonbuk University, Korea
- UCSB, Solid State Lighting and Energy Center, USA
- Pohang University of Science and Technology (POSTECH), Korea
- Advanced Optoelectronic Devices Laboratory, National Taiwan University
- Department of Appl. Math. and Phys., State University, Vladimir, Russia
- National Chiao Tung University, Taiwan
- Graduate School of Science and Engin., Tokyo Inst. of Technology
- Semiconductor Device Laboratory, Yamaguchi University, Ube, Japan
- Korea Polytechnic University, Siheung City, Korea
- Academic Physical Technological University, RAS, St.Petersburg, Russia
- Ching Yun University, Taiwan

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- School of ECE, Georgia Institute of Technology, GA, USA
- Tyndall University, Ireland
- Electrical & Engineering Department, University of Delaware, DE, USA
- Departm. of Electronic Sci. & Engin., Kyoto Univ., Group of Prof. Kawakami
- College of Optics and Photonics, University of Central Florida, FL, USA
- National Cheng Kung University, Taiwan
- Departm. of Materials Sci. and Engin., Meijo University, Nagoya, Japan
- Departm. of Electrical Engineering, National Central Univ., Jhongli, Taiwan
- Youngnam University, Korea

Customers from research centers and LED companies. We are grateful to those of our SimuLED™ customers from who permitted us to refer their names.

- Central Electronic Engineering Research Institute, India
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- Bridgelux, USA
- Epi-Center, Russia
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- Palo Alto Research Center, CA, USA
- Korea Advanced Nano Fab Center (KANC)
- UV Craftory Co., Ltd.
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